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APPLICANTS

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\*\* CONTINUING DATA \*\*\*\*\*  
*SRM NONE*

\*\* FOREIGN APPLICATIONS \*\*\*\*\*  
 JAPAN P2002-189086 06/28/2002  
*SRM*

IF REQUIRED, FOREIGN FILING LICENSE GRANTED  
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Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY JAPAN	SHEETS DRAWING 4	TOTAL CLAIMS 20	INDEPENDENT CLAIMS 3
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged Examiner's Signature <i>SRM</i> Initials <i>SRM</i>				

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TITLE  
 Exposure method, mask fabrication method, fabrication method of semiconductor device, and exposure apparatus

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